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PATENT APPLICATION  
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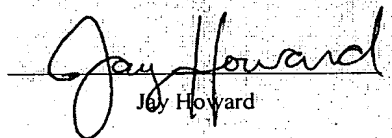


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Ajit P. Paranjpe et al.  
Serial No.: 09/864,714  
Filing Date: May 23, 2001  
Group Art Unit: 2814  
Examiner: Rao, Shrinivas H.  
Title: *Atomic Layer Deposition For Fabricating Thin Films*

**MAIL STOP - AMENDMENT**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

I hereby certify that this correspondence is being deposited with the United States Postal Service as Express Mail No. **EV351293258US** in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313, on July 23, 2004.

  
Jay Howard

**RESPONSE TO OFFICE ACTION**

Dear Sir:

In response to the Office Action mailed April 23, 2004 (Paper No. 10), Applicants respectfully request that the Examiner reconsider the application in view of the following amendments and remarks:

**Amendments to Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 7 of this paper.